PA-10c

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Application No. 10/684,451	Prepared by	JB	Tracking Number 5996418
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b. Applicant(s)	g. Disclaimer	l. Print Fig.	q. PTOL-85b
c. Continuing Data	h. Microfiche Appendix	m. Searched Column	r. Abstract
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

Sheet 2 of 2

Complete if Known	
Application Number	10/684,457
Filing Date	October 15, 2003
First Named Inventor	Chul-Sung KIM, et al
Art Unit	
Examiner Name	
Attorney Docket Number	239/162 DIV.1

NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.[1]	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T[2]
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		LO, et al, MOS Characteristics of Fluorinated ..., IEEE Electron Device Ltrs, 11(11):511-513, (1990)	
		WRIGHT, et al., Hot-Electron Immunity of SiO2 Dielectrics with Fluorine.., IEEE, pp. 347-348, (1989)	
		HOOK, et al., Correlation Between Fixed Positive Charge and Hot-Electron., IEEE, pp. 471-473, (1997)	

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